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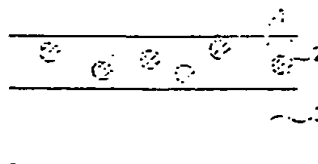
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⑤④ Surface roughening method.

⑤⑦ A surface roughening method, preferably for a substrate
of a solar cell, comprising coating the substrate with a photo-
resist material having light-shielding particles mixed therein,
exposing and developing the photoresist coating and then
etching the substrate with a suitable etchant.

FIG. 1(c)





European Patent
Office

EUROPEAN SEARCH REPORT

0180222

Application Number

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DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int. Cl.4)
A	EP-A-0 014 759 (IBM CORP.) * Abstract * ---	1	H 01 L 21/308 H 01 L 31/02 G 03 F 7/00
A	J. VAC. SCI. TECHNOL., vol. 1, no. 4, October/December 1983, pages 1109-1112, American Vacuum Society; H.W. DECKMAN et al.: "Applications of surface textures produced with natural lithography" * Whole article * ---	1	
A	US-A-4 407 695 (H.W. DECKMAN et al.) * Abstract; claims 1,2 * -----	1	
The present search report has been drawn up for all claims			TECHNICAL FIELDS SEARCHED (Int. Cl.4)
			H 01 L G 03 F
Place of search THE HAGUE		Date of completion of the search 29-07-1988	Examiner ZOLLFRANK G.O.
CATEGORY OF CITED DOCUMENTS			
<p>X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document</p> <p>I : theory or principle underlying the invention E : earlier patent document, but published on, or / after the filing date D : document cited in the application L : document cited for other reasons</p> <p>& : member of the same patent family, corresponding document</p>			